

10/706624  
Classification: 219/121.430  
Status: 30 - DOCKETED NEW CASE - READY FOR EXAMINATION  
Title: METHOD FOR SEMICONDUCTOR WAFER ETCHING

Examiner: PASCHALL, MARK  
Inventor: SHIMIZU , AKIRA, et al

GAU: 3742

Bib Data report

**Application Title:**METHOD FOR SEMICONDUCTOR WAFER ETCHING

**Application Num:** 10/706624 **Filing Date:**11/12/2003

**Effective Filing:**11/12/2003

(Location History)    (Foreign/Continuity Data)

**Status:** 30/DOCKETED NEW CASE - READY FOR EXAMINATION   **Status Date:**  
08/03/2004

**Patent Number:** Not Issued   **Issue Date:** N/A   **Date of Abandonment:** N/A  
**Confirmation Number:**7986   **PALM Location:**

**Examiner:**61092   **PASCHALL, MARK Assignment Data)**   **Group Art Unit:**  
3742   **Class/Subclass:** 219/121.430

**State or Country:**JAPAN   **Sheets/Drawing:** 1   **Total Claims:**17  
**Independent Claims:**3

▼ **Inventors:**

**Last name, First name:**   **City:**   **Country or State:**  
SHIMIZU, AKIRA   TOKYO   JAPAN  
NANBA, KUNITOSHI   TOKYO   JAPAN

**Attorneys:** ALL   **Attorney Docket No:**ASMJP.104DV1

**Interference No:**   **Lost Case:**No   **Unmatched Petition:**No   **L&R Code:**1



## UNITED STATES PATENT AND TRADEMARK OFFICE

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## \*BIBDATASHEET\*

Bib Data Sheet

CONFIRMATION NO. 7986

SERIAL NUMBER 10/706,624	FILING DATE 11/12/2003	CLASS 219	GROUP ART UNIT 3742	ATTORNEY DOCKET NO. ASMJP.104DV1
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## APPLICANTS

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## \*\* CONTINUING DATA \*\*\*\*\*

This application is a DIV of 10/068,092 02/05/2002 PAT 6,764,572 OK.

N

## \*\* FOREIGN APPLICATIONS \*\*\*\*\* OK

JAPAN 2001-056685 03/01/2001 N

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 02/20/2004

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY	SHEETS DRAWING 1	TOTAL CLAIMS 17	INDEPENDENT CLAIMS 3
35 USC 119 (a-d) conditions met	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after allowance				
Verified and Acknowledged	<i>M. H. Teller</i> Examiner's Signature	<i>MH</i> Initials			

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## TITLE

Method for semiconductor wafer etching

<input type="checkbox"/> All Fees
<input type="checkbox"/> 1.16 Fees ( Filing )
<input type="checkbox"/> 1.17 Fees ( Processing Ext. of time )

FILING FEE FEES: Authority has been given in Paper  
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